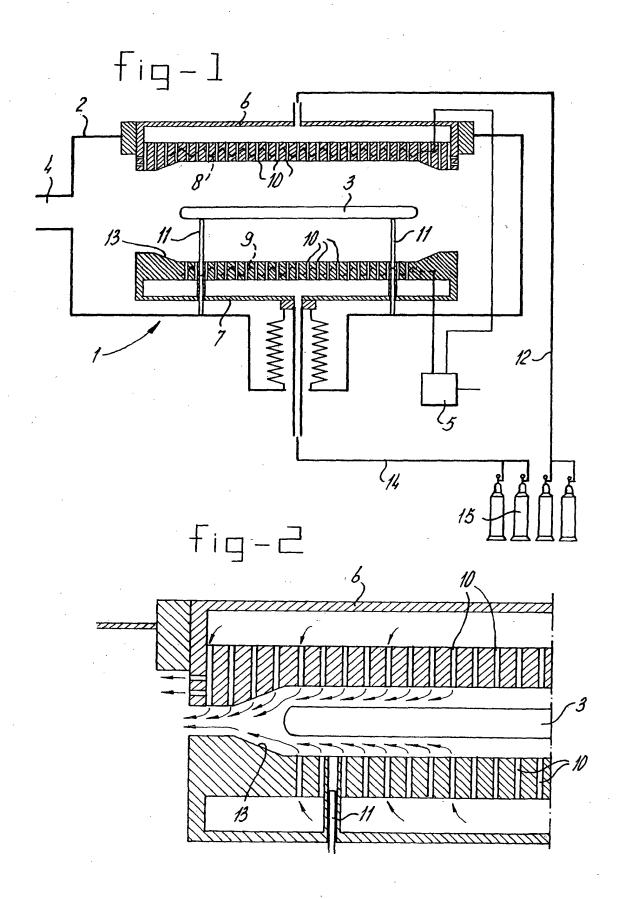
METHOD AND APPARATUS FOR SUPPORTING A
SEMICONDUCTOR WAFER DURING PROCES
Gramneman et al.

Appl. No.: Unknown

Atty Docket: ASMINT.002C3



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